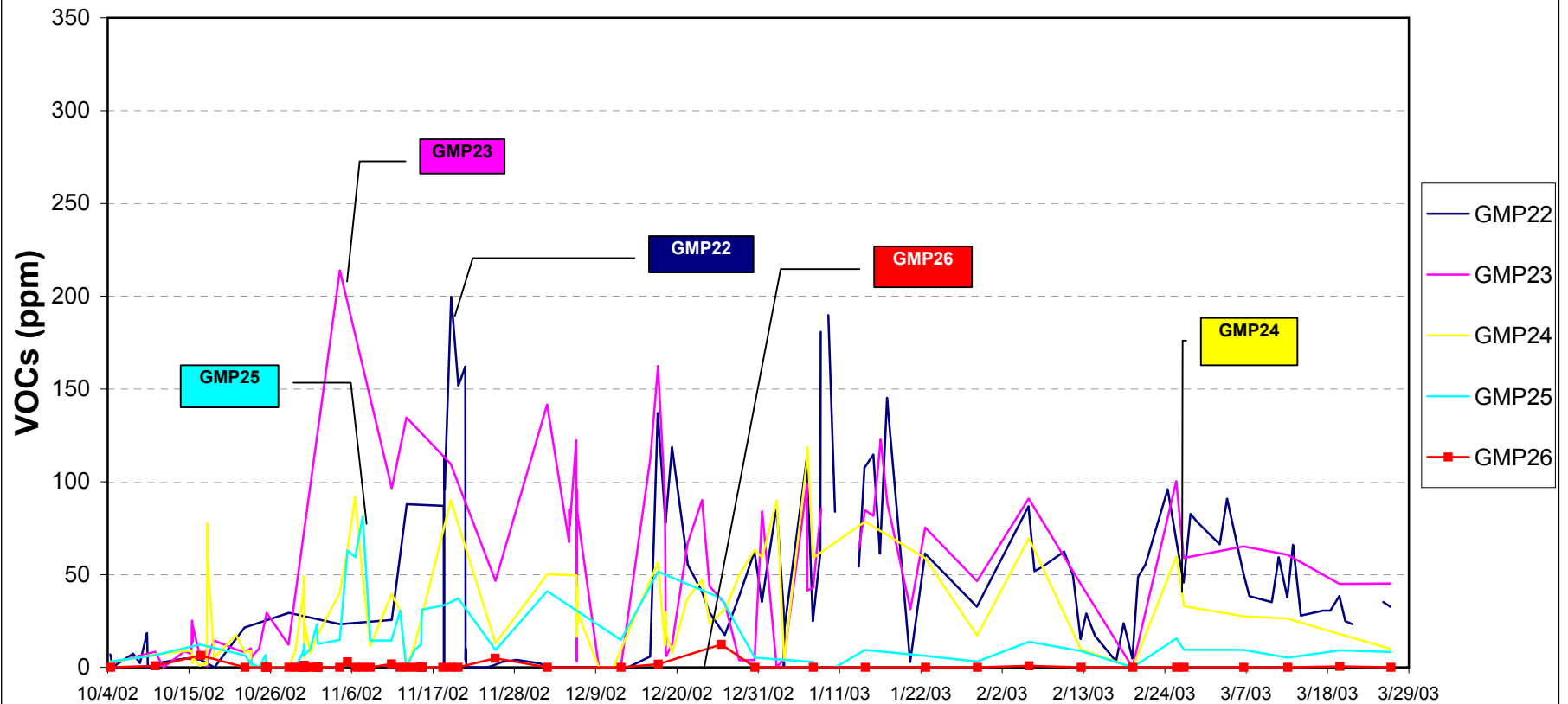


Gas Monitoring Probe (GMP) Operational Monitoring within UCSF Compound



Notes: In the course of operating the Landfill Gas Removal System the "Extraction Monitoring and Maintenance Plan" (EMMP) requires some points to be monitored more frequently than weekly. The monitored points will vary according to the wells where extraction is occurring. This figure is a plot of the data collected for the EMMP.